S23	5	(silicate clay) same (kiln firing insolubili\$8 kiln-fired) near3 (both two) near3 (layer coat\$3)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/08/11 14:39
S24	2	"60147276"	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR ·	ON	2005/08/11 14:39
S25	78	("6214466" joedicke.in.)	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/02/28 11:50
S26	5	S25 and (pore porous)	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/02/28 11:52
S27	4364	algae and (pore porous)	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/02/28 11:53
S28	4795	algae and (pore porous void microvoid micropor\$5)	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/02/28 11:54
S29	209	S28 and roof\$3	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/02/28 11:55
S30	5588	(algae alg\$3cid\$3) and (porosity pore porous void microvoid micropor\$5)	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/02/28 12:09

S31	39	S30 and roof\$3 near9 granule	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR ·	ON	2006/02/28 12:11
S32	5603	(algae alg\$3cid\$3) and (porosity pore porous void microvoid micropor\$5 (gas adj forming))	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/02/28 12:10
S33	6749	(algae alg\$3cid\$3) and (porosity pore porous void microvoid micropor\$5 (gas adj forming) perborate persulfate borohydride azide)	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR .	ON	2006/02/28 12:10
S34	2150	(algae alg\$3cid\$3) and (((pore void microvoid micropor\$5 gas) near3 forming) perborate persulfate borohydride azide)	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/02/28 12:15
S35	8	S34 and roof\$3 near9 granule	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/02/28 12:15
S36	40	S33 and roof\$3 near9 granule	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/02/28 12:12
S37	30	S34 and roof\$3	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/02/28 12:16
S38	11350	(algae alg\$3cid\$3 fungi\$4) and (((pore void microvoid micropor\$5 gas) near3 forming) perborate persulfate borohydride azide)	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/02/28 12:15

S39	8846	(algae alg\$3cid\$3 fungi\$4) and (((pore void microvoid micropor\$5 gas) near3 forming) ((hydrogen metal potassium sodium alkali) near3 (perborate persulfate borohydride azide)))	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/02/28 12:18
S40	6	S39 and roof\$3 near3 granul\$3	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/02/28 12:19
S41	12274	(algae alg\$3cid\$3 fungi\$4) and (porous ((pore void microvoid micropor\$5 gas) near3 forming))	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	ON .	2006/02/28 12:23
S42	26	S41 and roof\$3 near3 granul\$3	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/02/28 12:24
S43	2401	(algae alg\$3cid\$3 fungi\$4) and (porous ((pore void microvoid micropor\$5 gas) near3 (forming form formation))) near9 (coat\$3 layer ceramic silicate)	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR .	ON	2006/02/28 12:28
S44	18	S43 and roof\$3 near3 granul\$3	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/02/28 12:24
S45	1	(algae alg\$3cid\$3 fungi\$4) and (pore void microvoid micropor\$5 gas) near3 (forming form formation) near9 (coat\$3 layer) near3 (ceramic silicate)	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/02/28 12:30
S46	7	(algae alg\$3cid\$3 fungi\$4) and (pore void microvoid micropor\$5 gas) near3 (forming form formation) same (coat\$3 layer) near3 (ceramic silicate)	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/02/28 12:31

S47	108	(algae algebroides funcies) and	US-PGPUB;	OR	ON	2006/02/28 12:38
347	106	(algae alg\$3cid\$3 fungi\$4) and (pore void microvoid micropor\$5 gas) near3 (forming form formation) and (coat\$3 layer) near3 (ceramic silicate)	USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	UK	ON	2000/02/20 12:30
S48	15	S47 and roof\$4	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/02/28 12:32
S49	93	S47 not S48	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/02/28 12:35
S50		(algae alg\$3cid\$3 fungi\$4) near9 (release sustained prolonged control\$4) and (pore void microvoid micropor\$5 gas) near3 (forming form formation) near3 (coat\$3 layer)	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/02/28 12:39
S51	16	(algae alg\$3cid\$3 mildew\$4 fungi\$4) near9 (release sustained prolonged control\$4) and (pore void microvoid micropor\$5 gas) near3 (forming form formation) near3 (coat\$3 layer)	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/02/28 12:42
S52	2636	(algae alg\$3cid\$3 mildew\$4 fungi\$4 anti\$1microbial anti\$1bacter\$4) near19 (pore void microvoid micropor\$5 porous)	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/02/28 12:46
S53	1991	(algae alg\$3cid\$3 mildew\$4 fungi\$4 anti\$1microbial anti\$1bacter\$4) near9 (pore void microvoid micropor\$5 porous)	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/02/28 12:44
S54	48	(algae alg\$3cid\$3 mildew\$4 fungi\$4 anti\$1microbial anti\$1bacter\$4) near3 (leach\$5 release) near9 (pore void microvoid micropor\$5 porous)	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/02/28 12:45

S55	267	(algae alg\$3cid\$3 mildew\$4 fungi\$4 anti\$1microbial anti\$1bacter\$4) near19 (pore void microvoid micropor\$5 porous gas) near9 (forming formation)	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/02/28 12:47
S56	220	(algae alg\$3cid\$3 mildew\$4 fungi\$4 anti\$1microbial anti\$1bacter\$4) near19 (pore void microvoid micropor\$5 porous gas) near3 (forming formation)	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/02/28 12:47
S57	144	(algae alg\$3cid\$3 mildew\$4 fungi\$4 anti\$1microbial anti\$1bacter\$4) near9 (pore void microvoid micropor\$5 porous gas) near3 (forming formation)	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/02/28 12:48
S58	119	(algae alg\$3cid\$3 mildew\$4 fungi\$4 anti\$1microbial anti\$1bacter\$4) near9 (pore void microvoid micropor\$5 porous gas) near (forming formation)	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR ·	ON	2006/02/28 12:59
S59	3	(algae alg\$3cid\$3 mildew\$4 fungi\$4 anti\$1microbial anti\$1bacter\$4) near3 (release leach\$3 control controlled controlling) near19 (pore void microvoid micropor\$5 porous gas) near (forming formation)	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/02/28 12:53
S60		S57 and roof\$3	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/02/28 12:53
S61	196	(algae alg\$3cid\$3 mildew\$4 fungi\$4 anti\$1microbial anti\$1bacter\$4) near19 (pore void microvoid micropor\$5 porous gas) near (forming formation)	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/02/28 12:53
S62	10	S61 and roof\$3	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/02/28 12:53

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S63	2	S62 not S60	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/02/28 12:53
S64	· 5	(algae alg\$3cid\$3 mildew\$4 fungi\$4 anti\$1microbial anti\$1bacter\$4) near9 ((effective increas\$4 control controlled sustained prolonged) near3 (release leach\$3)) same (pore void microvoid micropor\$5 porous gas) near (forming formation)	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/02/28 13:04
S65	· 6	(algae alg\$3cid\$3 mildew\$4 fungi\$4 anti\$1microbial anti\$1bacter\$4) near9 (effective increas\$4 control controlled sustained prolonged) same (pore void microvoid micropor\$5 porous gas) near (forming formation) near9 (coat\$3 ceramic silicate layer film)	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/02/28 13:10
S66	0	(algae alg\$3cid\$3 mildew\$4 fungi\$4 anti\$1microbial anti\$1bacter\$4) same (pore void microvoid micropor\$5 porous gas) near (forming formation) near9 (coat\$3 layer film) near3 (ceramic silicate)	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/02/28 13:12
S67	1	(algae alg\$3cid\$3 mildew\$4 fungi\$4 anti\$1microbial anti\$1bacter\$4) and (pore void microvoid micropor\$5 porous gas) near (forming formation) near9 (coat\$3 layer film) near3 (ceramic silicate)	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/02/28 13:19
S69	12	"4,378,408"	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/02/28 14:19
S70	4	(algae alg\$3cid\$3 mildew\$4 fungi\$4 anti\$1microbial anti\$1bacter\$4) and S69	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/02/28 13:20

S71	2	"20040255548"	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/02/28 13:54
S72		"3528842"	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/02/28 13:54

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